| Course | | L-T-P - | | ar of |
|-----------------------|---|-------------------------|----------|-----------------------|
| code | | Credits | | duction |
| EE404 | | 3-0-0-3 | 2 | 016 |
| Dronoquio | AUTOMATION | | | |
| Prerequis Course O | | | - | |
| Course | To impart knowledge about Industrial instrumentation and | lautomat | ion | |
| Syllabus: | • To impart knowledge about industrial instrumentation and | automat | | |
| v | characteristic of instrumentation- Transducers: Characteristic | s Appli | cations | – Nano |
| | tation - signal conditioning, MEMS, Virtual instrumentation | | | |
| | - sequence control, PLC | | | <i>J</i> ~~~~ |
| | Outcome: | | | |
| - | completion of the course, the students will be able to: | | | |
| i. | Select instruments and transducers for various physical variab | les. | | |
| ii. | Get an insight on data acquisition, processing and monitoring | system | | |
| iii. | Design various signal conditioning systems for transducers. | | | |
| iv. | Analyze dynamic responses of various systems. | | | |
| v. | Get the concepts of virtual instrumentation | | | |
| vi. | Understand the programming realization of PLC | | _ | |
| Text book | | | | |
| | rtis D Johnson," Process Control Instrumentation Technology | | | |
| | beblin E.O, 'Measurement Systems: Application and Design, 1 | Fourth E | lition, | McGraw |
| | II, Newyork, 1992 | | | Deve I tal |
| | /S. Murty, 'Transducers and Instrumentation' Second Edition w Delhi, 2013 | I, PHI LO | arning | PVI LIA |
| | adhuchhanda Mitra, Samarjit Sengupta, 'Programmable Logic (| Controller | 's and I | ndustrial |
| | tomation An Introduction', Penram International Publishing (Ir | | | |
| | ckell. P. Groover 'Automation, Production and computer in | | | |
| | entice Hall of India, 1992 | | | |
| | tranabis, D., 'Principles of Industrial Instrumentation', Secon | d Editior | Tata | McGraw |
| Hi | ll Publishing Co. Ltd New Delhi | | | |
| 7. Ro | ll Publishing Co. Ltd New Delhi bert B. Northrop, 'Introduction to instrumentation and measure | <mark>ment</mark> s', C | RC, Ta | ylor and |
| Fra | ancis 2005 | | | |
| Reference | | | | |
| | K.McMillan, 'Process/Industrial Instrument and control and ha | and book | ' McGı | aw Hill, |
| | w York,1999 | | ~ | |
| | chael P .Lucas, 'Distributed Control system', Van Nastrant F | Reinhold | Compa | ny, New |
| Yo | | | | |
| | Course Plan | | | |
| Module | Contents | E | lours | Sem. Exam Marks |
| _ | Introduction to Process Control - block diagram of process co loop, definition of elements. Sensor time response - first | | 6 | 15% |
| Ι | second order responses. | | 0 | 13% |

| | factors influencing choice of transducer | | |
|-----|---|-----|-----|
| П | Applications of Transducers | | |
| | Displace measurement: Resistance potentiometer, Capacitive and | | |
| | Inductive. Capacitive differential pressure measurement | | |
| | Torsional, shearing stress and rotating shaft Torque measurement | 8 | 15% |
| | using strain gauge. Flow measurement :Hotwire anemometer, | | |
| | constant resistance Constant current type Eddy current sensors, | A | |
| | Variable reluctance tachometers | V.L | |
| | Phase measurement : Analog and digital phase detectors | T | |
| | Nano Instrumentation | 1.5 | |
| | FIRST INTERNAL EXAMINATION | | · |
| III | Signal conditioning circuits-Instrumentation amplifiers- | | |
| | Unbalanced bridge. Bridge linearization using op amp | | 15% |
| | Precision rectifiers, Log amplifiers, Charge amplifiers, Isolation | 7 | |
| | amplifier, Switched capacitor circuits, Phase sensitive detectors, | | |
| | Noise problem in instrumentation and its minimisation | | |
| IV | Micro Electromechanical system (MEMS) | 7 | |
| | Advantages and Applications, MEMS micro sensors and actuators, | | |
| | Manufacturing process: Bulk micro machining and surface | | |
| | micromachining, MEMS accelerometers | | 15% |
| | Virtual instrumentation system: architecture of virtual instruments | | |
| | – Virtual instruments and traditional instruments – concepts of | | |
| | graphical programming | | |
| | SECOND INTERNAL EXAMINATION | | |
| | Overview of Automation System - Architecture of Industrial | | |
| | Automation Systems, Different devices used in Automation | 7 | 20% |
| V | Actuators, definition, types, selection. | | |
| | Pneumatic, Hydraulic, Electrical, Electro-Pneumatic and valves, | | |
| | shape memory alloys | | |
| | Introduction to Sequence Control, PLCs - Working, Specifications | 7 | |
| VI | of PLC Onboard/Inline/Remote IO's, Comparison of PLC & PC, | | 20% |
| | Relay Ladder Logic- PLC Programming- realization of AND, OR | | |
| | logic, concept of latching, Introduction to Timer/Counters, | ' | |
| | Exercises based on Timers, Counters. Basic concepts of SCADA, | | |
| | DCS and CNC | | |
| | END SEMESTER EXAM | | |

1-1

QUESTION PAPER PATTERN:

Maximum Marks: 100

Exam Duration: 3Hourrs.

Part A: 8 compulsory questions.

One question from each module of Modules I - IV; and two each from Module V & VI.

Student has to answer all questions. $(8 \times 5)=40$

Part B: 3 questions uniformly covering Modules I & II. Student has to answer any 2 from the 3 questions: $(2 \times 10) = 20$. Each question can have maximum of 4 sub questions (a,b,c,d), if needed.

Part C: 3 questions uniformly covering Modules III & IV. Student has to answer any 2 from the 3 questions: $(2 \times 10) = 20$. Each question can have maximum of 4 sub questions (a,b,c,d), if needed.

Part D: 3 questions uniformly covering Modules V & VI. Student has to answer any 2 from the 3 questions: $(2 \times 10) = 20$. Each question can have maximum of 4 sub questions (a,b,c,d), if needed.

